



GAU1765  
#3  
1-5-2000

PATENT

UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: BRUNNER ET AL 1  
SERIAL NO: 09/425,694  
FILED: OCTOBER 22, 1999 GROUP: 1765  
TITLE: PROCESS FOR THE WET TREATMENT OF SEMICONDUCTOR  
WAFERS

SUBMISSION OF INFORMATION DISCLOSURE STATEMENT  
OF DR. WOLFGANG STAUDACHER

ATT: BOX NON FEE AMENDMENT  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

Applicants wish to bring to the attention of the Patent Examiner the attached Information Disclosure Statement, duly signed by Dr. Wolfgang Staudacher and the four (4) references listed on the enclosed Form PTO-1449 and attached thereto.

The relevance of these references is that they are cited in the German Office Action and in the present application and may be material to the examination of the application.

Since this Information Disclosure Statement is being filed prior to a first Office Action, it is believed that no fee is due. However, if it is determined that a fee is due, the Commissioner is hereby authorized to charge, or to credit any over payment, to our Deposit Account Number 03-2468.

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
BRUNNER ET AL - 1 :  
Serial Number 09/425,694 : Group Art Unit: 1765  
Filed: 10/22/99 :  
For: PROCESS FOR THE WET :  
CHEMICAL TREATMENT OF SEMI- :  
CONDUCTOR WAFERS :

Information Disclosure Statement

Honorable Commissioner of Patents and Trademarks  
Washington, D.C. 20231

Sir or Madam:

I, Wolfgang Staudacher, associated with the preparation and prosecution of the above-identified application, residing at Seebauerstraße 4, 81735 München, Germany, wish to call the attention of the Patent Examiner to the references enumerated on the enclosed PTO Form-1449.

I believe the documents enumerated on the enclosed Form PTO-1449 and attached thereto, are cited in the German Office action and in the enclosed application and may be material to the examination of the application.

Therefore, it is respectfully requested that the foregoing Information Disclosure Statement be considered by the Examiner and incorporated into the file of this application.

I wish to comment as follows concerning the prior art references enumerated on PTO Form-1449:

EP 0 701 275 A2 is already in English language.

For JP 4-26120 A an English Abstract is enclosed

For Proceedings of the second Int. Symp. On Cleaning Techn. In Semiconductor Device Manufacturing, Electrochem. Soc., 1992, pp. 18.25, an English ~~Derwent~~ Abstract is enclosed.

M. Meuris et al., Solid State Technologie, July 1995, p.109 is already in English language.

Signed this 8<sup>th</sup> day of December, 1999.

  
Dr. Wolfgang Staudacher